



Title: SHALLOW TRENCH ISOLATION PROCESS AND STRUCTURE WITH  
MINIMIZED STRAINED SILICON CONSUMPTION

Inventor(s): Xiang et al.

Appl. No.: 10/755,602

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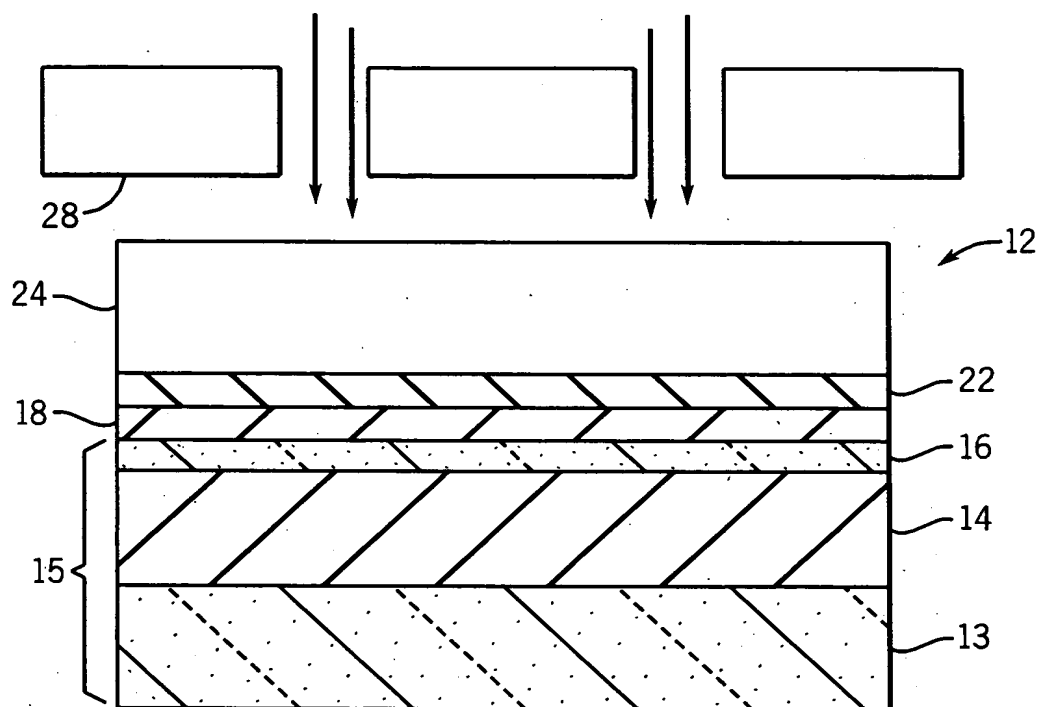


FIG. 1

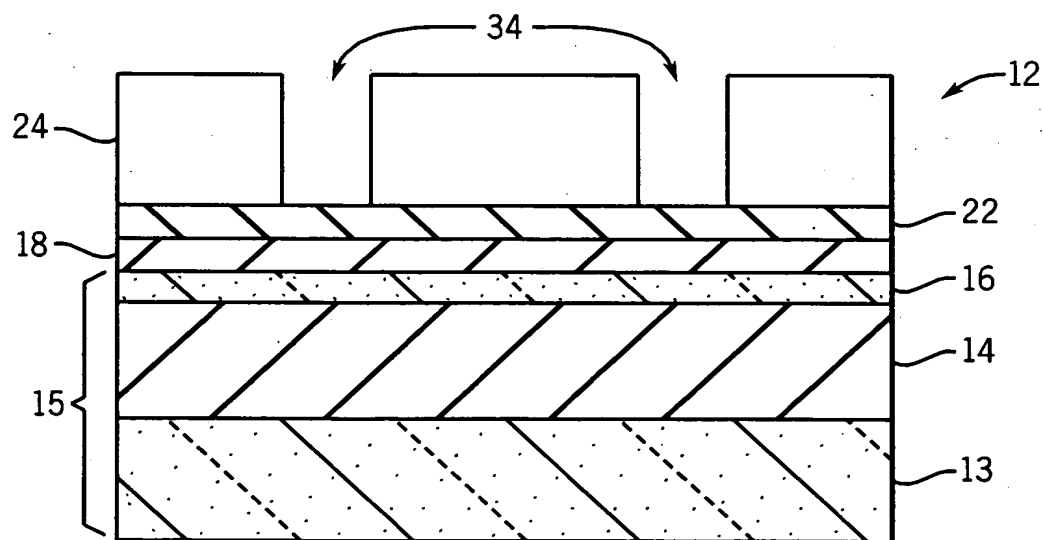


FIG. 2

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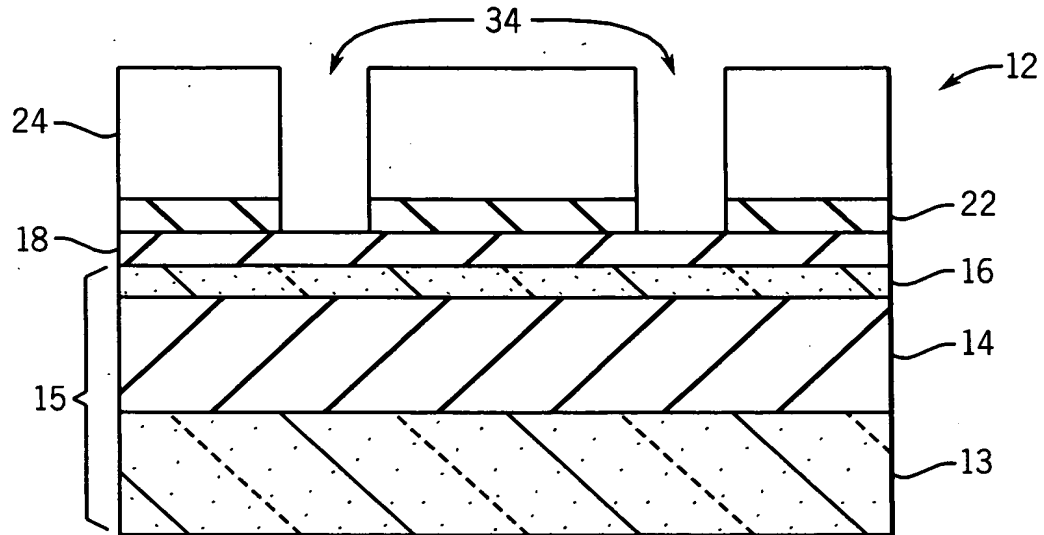


FIG. 3

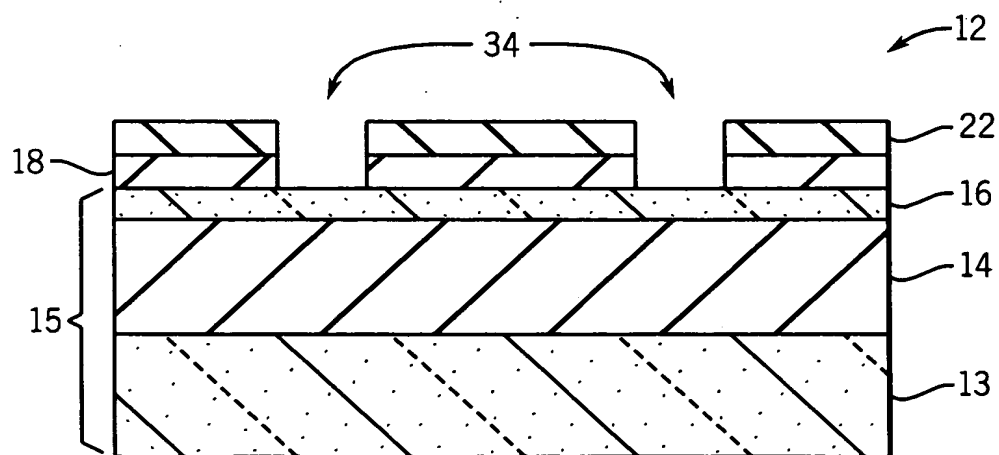


FIG. 4

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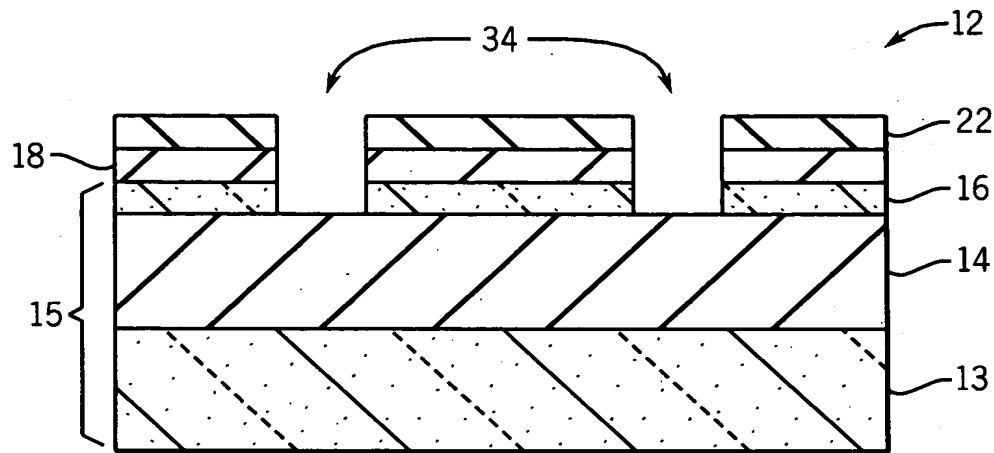


FIG. 5

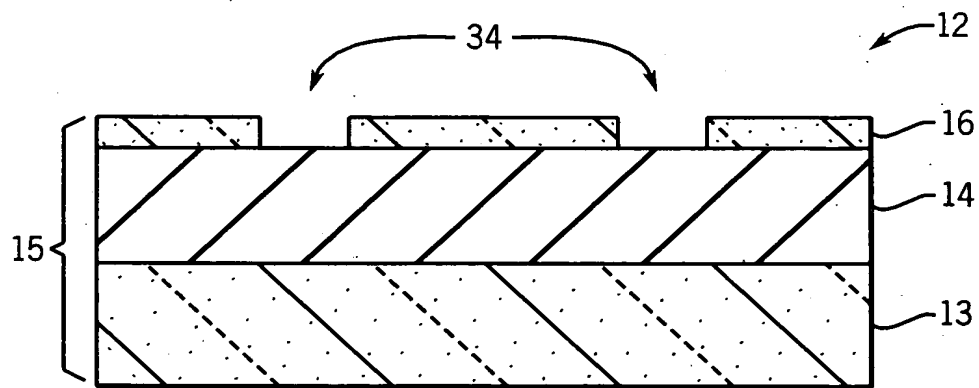


FIG. 6

FIG. 8

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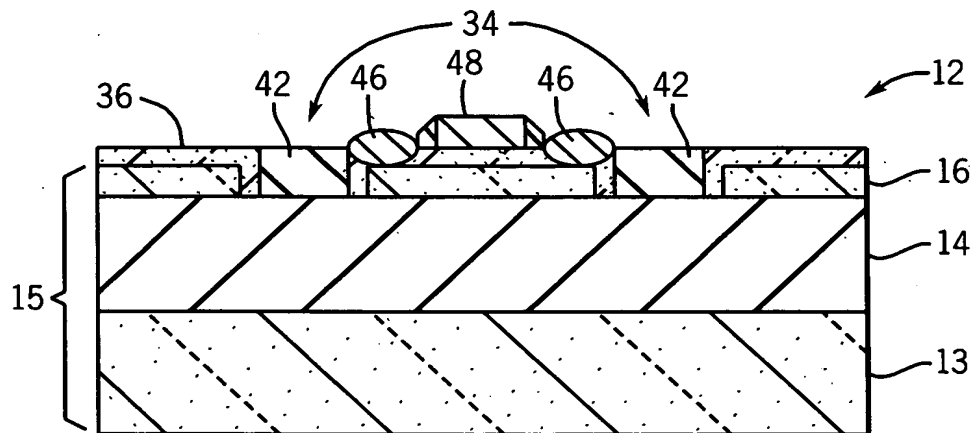


FIG. 9

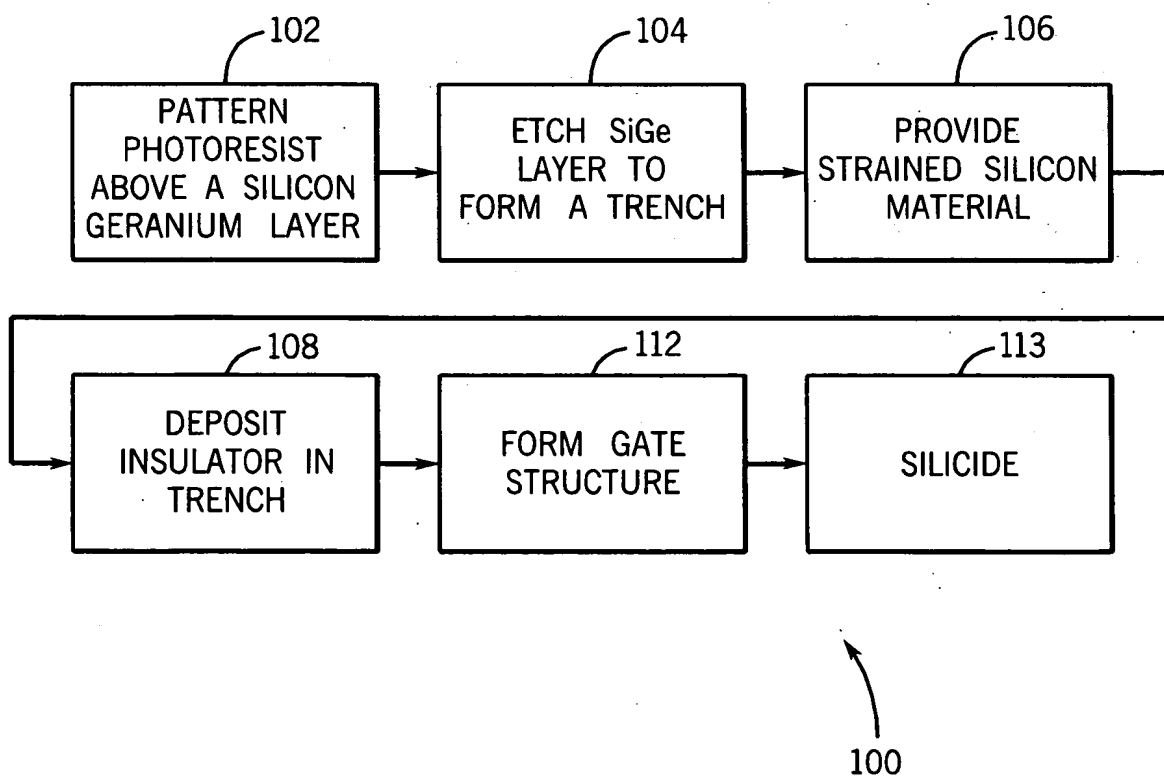


FIG. 10

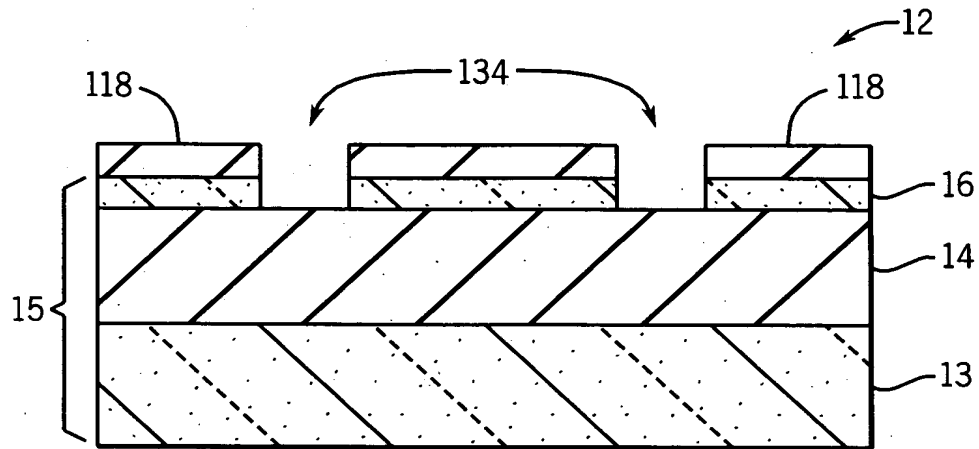


FIG. 11

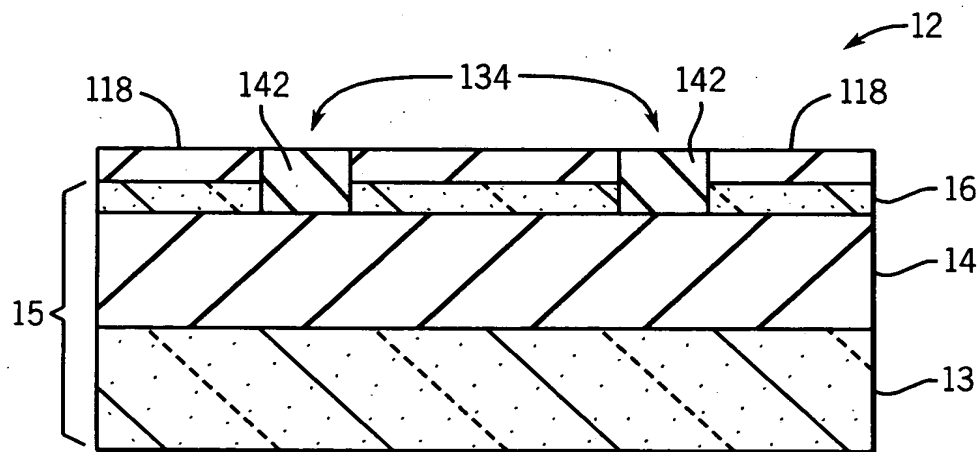


FIG. 12

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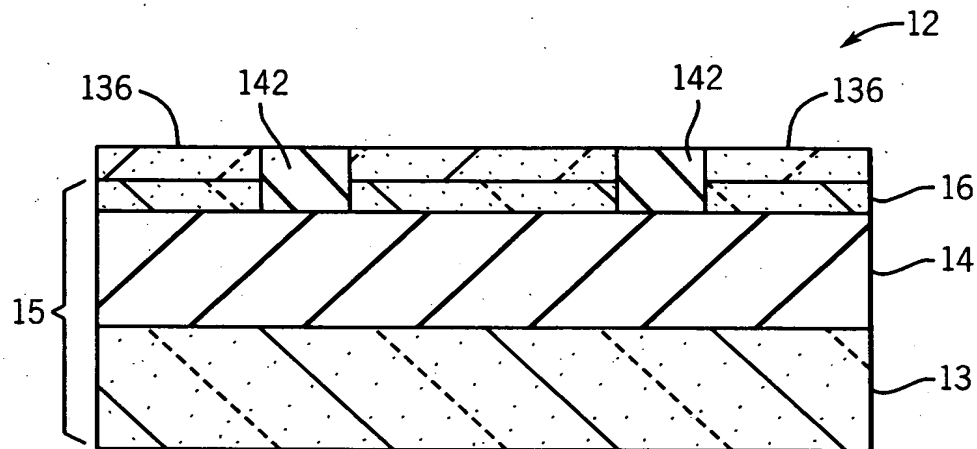


FIG. 13

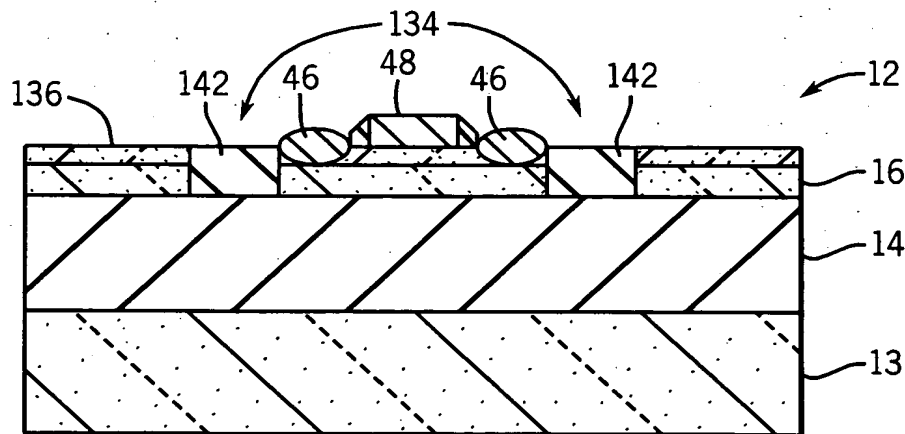


FIG. 14

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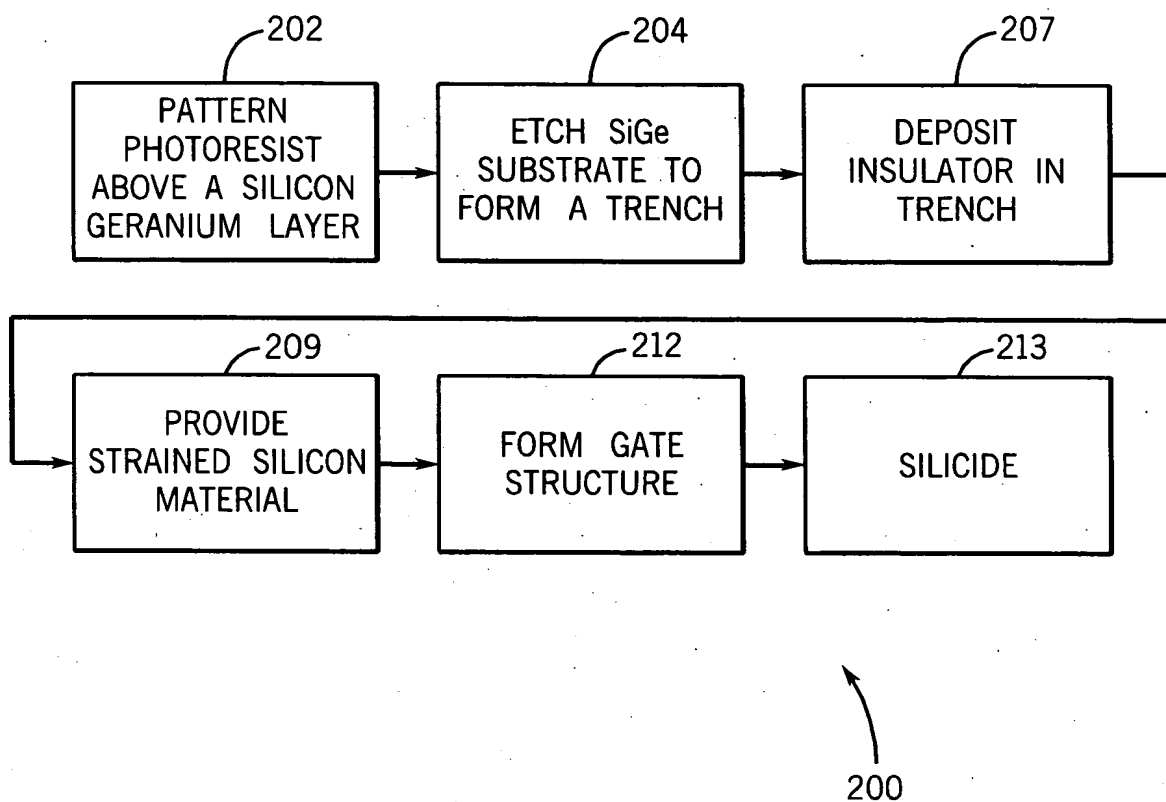


FIG. 15